

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takao SAITO et al.

Group Art Unit: 1762

Application No.: 10/766,806

Filed: January 30, 2004

Docket No.: 115556

For: METHOD AND SYSTEM FOR FORMING THIN FILMS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. The references 1-4 were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.
- ☒ 3. In accordance with 37 CFR §1.98(a)(2)(i), copies of any U.S. patents and patent application publications are not attached.

Respectfully submitted,



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<p>DEPOSIT ACCOUNT USE AUTHORIZATION</p> <p>Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>

Sheet 1 of 1Form PTO-1449
(REV. 8-83)US Dept. of Commerce
PATENT & TRADEMARK OFFICEATTY DOCKET NO.
115556APPLICATION NO.
10/766,806

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANTS
Takao SAITO et al.FILING DATE
January 30, 2004GROUP
1762

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
	1.	US 2002/0170495 A1	11/21/2002	NAKAMURA et al.		
	2.	US 2002/0182319 A1	12/5/2002	BEN-MALEK et al.		
	3.	5,236,511	8/17/1993	ETZKORN et al.		

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	4.	Frank Jansen et al.; "Thin film deposition on inside surfaces by plasma enhanced chemical vapor deposition"; XP000474735; Thin Solid Films, Elsevier, Vol. 252, No. 1; November 15, 1994; pp 32-37

EXAMINER

DATE CONSIDERED

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: November 19, 2004